Dr. Stefan Saager was born in 1985. He studied physics at TU Dresden and graduated with cathodoluminescence investigations of crystal defects in silicon at low temperatures in 2010. Since then he is a scientific associate at the Fraunhofer Institute for Organic Electronics, Electron Beam and Plasma Technology FEP in Dresden. His research interests include the development and the optimization of new vacuum based deposition methods as well as the simulation of thermal processes. In 2015, Stefan finished his PhD thesis in the topic of deposition and crystallization of silicon thin films by using e-beam technology.